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(54) **NITRIDE SEMICONDUCTOR LED AND FABRICATION METHOD THEREOF**

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(57) **ABSTRACT**

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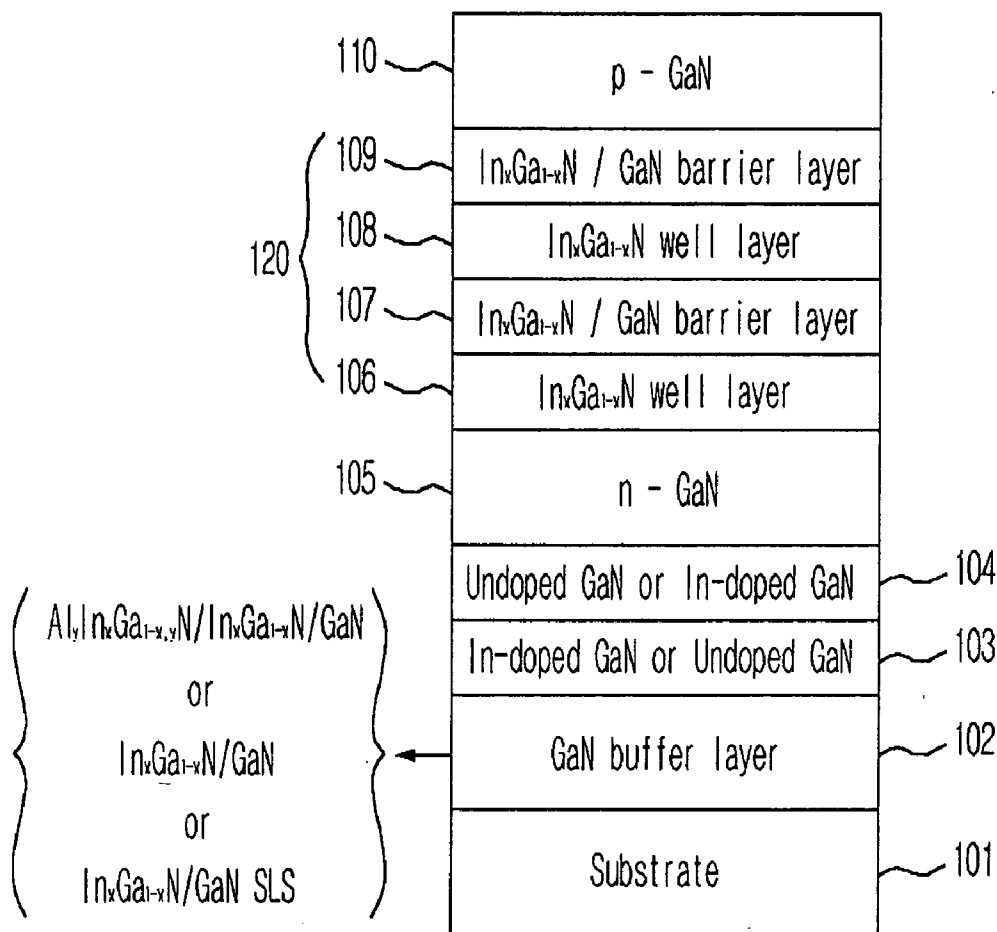
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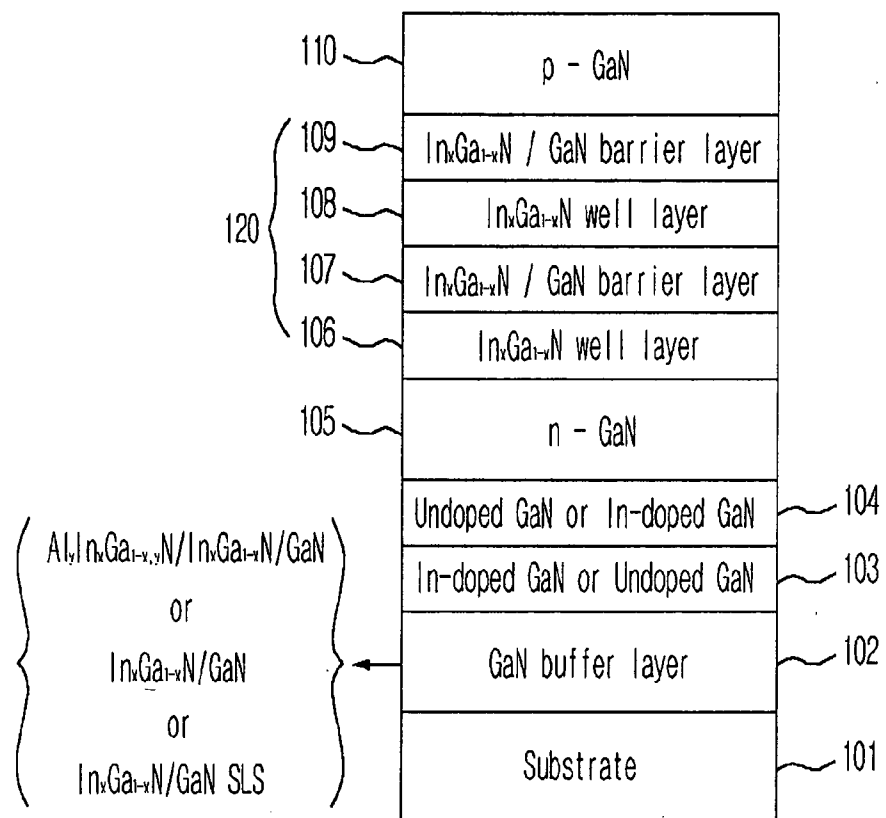
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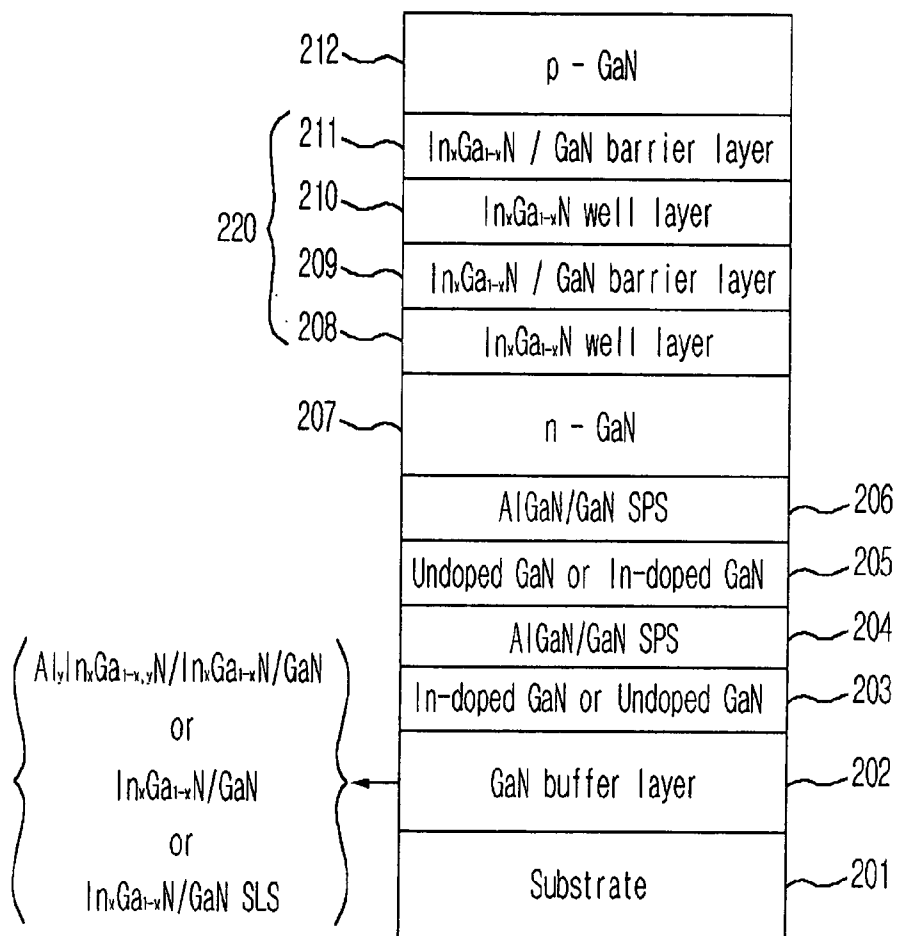
Disclosed a nitride semiconductor LED including: a substrate; a GaN-based buffer layer formed on the substrate; $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ short period superlattice (SPS) layers formed on the GaN-based buffer layer in a sandwich structure of upper and lower parts having an undoped GaN layer or an indium-doped GaN layer interposed therebetween (Here, $0 \leq y \leq 1$); a first electrode layer of an n-GaN layer formed on the upper $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ SPS layer; an active layer formed on the first electrode layer; and a second electrode layer of a p-GaN layer formed on the active layer.



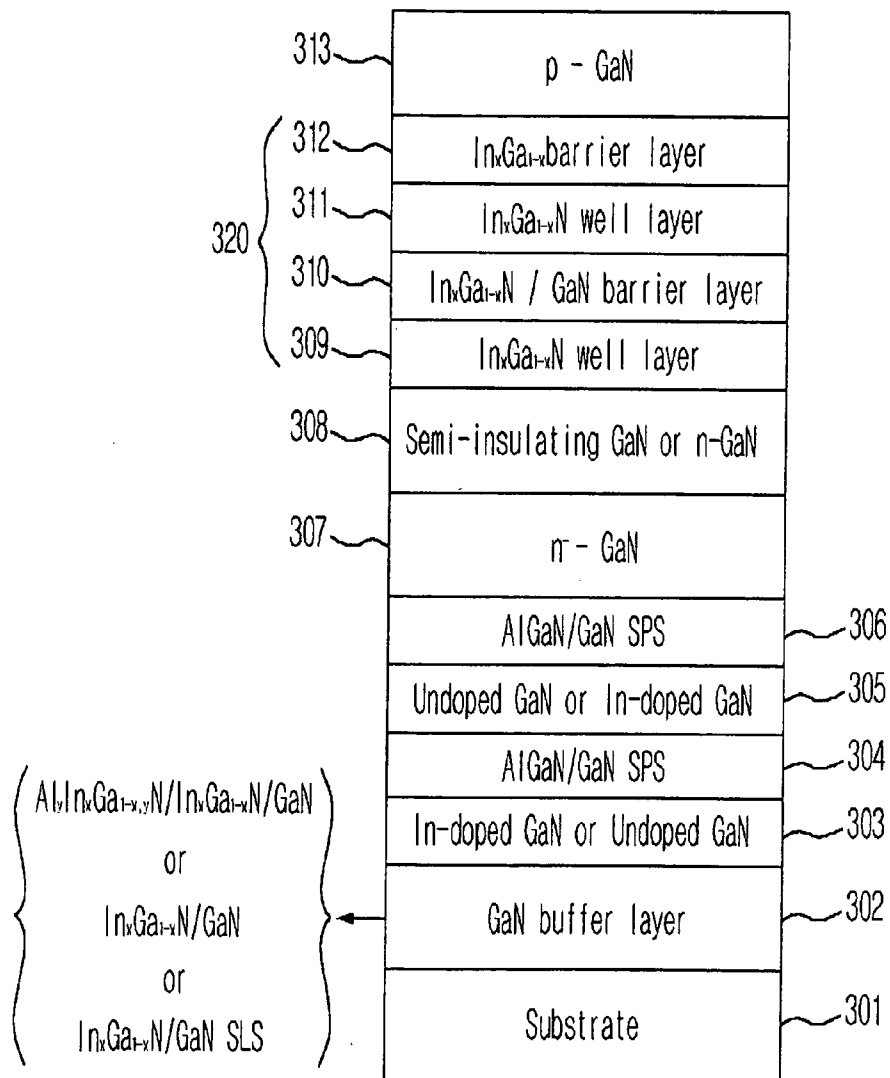
[FIG. 1



[FIG. 2]



[FIG. 3]



NITRIDE SEMICONDUCTOR LED AND FABRICATION METHOD THEREOF

TECHNICAL FIELD

[0001] The present invention relates to a nitride semiconductor, and more particularly, to a GaN-based nitride semiconductor light emitting device (LED) and a fabrication method thereof.

BACKGROUND ART

[0002] Generally, a GaN-based nitride semiconductor is applied to electronic devices that are high-speed switching and high power devices such as optic elements of blue/green LEDs, MESFET, HEMT, etc. In particular, the blue/green LED is under a state in which mass-production has been already progressed and a global sale is being exponentially increased.

[0003] The above-mentioned conventional GaN-based nitride semiconductor light emitting device (LED) is grown-up usually on a sapphire substrate or a SiC substrate. Further, at a low growth temperature, an $\text{Al}_y\text{Ga}_{1-y}\text{N}$ polycrystalline layer is grown-up on the sapphire substrate or the SiC substrate as a buffer layer. After that, at a high temperature, an undoped GaN layer, an n-GaN layer doped with silicon over a $1 \times 10^{17}/\text{cm}^3$ concentration or a combined n-GaN layer thereof is formed on the buffer layer as a first electrode layer. Additionally, on an Mg-AlGaN cladding layer is formed an Mg-GaN layer as a second electrode layer to complete the GaN-based nitride semiconductor LED. Also, a light emitting layer (multi-quantum well active layer) is sandwiched between the first electrode layer and the second electrode layer.

[0004] However, the above-constructed conventional nitride semiconductor LED has a crystal defect of a very high value of about $10^8/\text{cm}^3$ or so, which is generated from an interface between the substrate and the buffer layer.

[0005] Accordingly, the conventional nitride semiconductor LED has a drawback in that an electric characteristic, specifically, leakage current under a reverse bias condition is increased, resulting in a fatal influence to the reliability of the device.

[0006] Also, the conventional nitride semiconductor LED has another drawback in that the crystal defect generated from the interface between the buffer layer and the substrate deteriorates crystallinity of the light emitting layer thereby lowering the light emitting efficiency.

DISCLOSURE OF THE INVENTION

[0007] An object of the present invention is to provide a nitride semiconductor LED and a fabrication method thereof for reducing a crystal defect generated due to a difference in a thermal expansion coefficient and a lattice constant between a substrate and a GaN-based single crystalline layer grown-up on the substrate, and improving crystallinity of the GaN-based single crystalline layer, to thereby improve the performance of the device and assure the reliability.

[0008] To achieve these and other advantages and in accordance with the purpose of the present invention, as embodied and broadly described, there is provided a nitride semiconductor LED including: a substrate; a GaN-based

buffer layer formed on the substrate; $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ short period superlattice (SPS) layers formed on the GaN-based buffer layer in a sandwich structure of upper and lower parts having an undoped GaN layer or an indium-doped GaN layer interposed therebetween (Here, $0 \leq y \leq 1$); a first electrode layer of an n-GaN layer formed on the upper $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ SPS layer; an active layer formed on the first electrode layer; and a second electrode layer of a p-GaN layer formed on the active layer.

[0009] According to another aspect of the present invention, there is provided a nitride semiconductor LED, including: a substrate; a GaN-based buffer layer formed on the substrate; a first electrode layer of an n⁺-GaN layer formed on the GaN-based buffer layer and containing a high concentration of dopants; an n-GaN layer formed on the first electrode layer and containing a low concentration of dopants; an active layer formed on the n-GaN layer; and a second electrode layer of a p-GaN layer formed on the active layer.

[0010] According to still another aspect of the present invention, there is provided a fabrication method of a nitride semiconductor LED, the method including the steps of: growing-up a GaN-based buffer layer on a substrate; forming $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ short period superlattice (SPS) layers on the GaN-based buffer layer in a sandwich structure of upper and lower parts having an undoped GaN layer or an indium-doped GaN layer interposed therebetween (Here, $0 \leq y \leq 1$); forming a first electrode layer of an n⁺-GaN layer containing a high concentration of dopants, on the upper $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ SPS layer; forming an active layer on the first electrode layer; and forming a second electrode layer of a p-GaN layer on the active layer.

BRIEF DESCRIPTION OF THE DRAWINGS

[0011] FIG. 1 is a sectional view illustrating a schematic construction of a nitride semiconductor LED according to a first embodiment of the present invention;

[0012] FIG. 2 is a sectional view illustrating a schematic construction of a nitride semiconductor LED according to a second embodiment of the present invention; and

[0013] FIG. 3 is a sectional view illustrating a schematic construction of a nitride semiconductor LED according to a third embodiment of the present invention.

BEST MODE FOR CARRYING OUT THE INVENTION

[0014] Hereinafter, preferred embodiments of the present invention will be described in detail with reference to accompanying drawings.

[0015] FIG. 1 is a sectional view illustrating a schematic construction of a nitride semiconductor LED according to a first embodiment of the present invention.

[0016] Referring to FIG. 1, the inventive nitride semiconductor LED includes a substrate 101; a GaN-based buffer layer 102 formed on the substrate 101; a first electrode layer of an n-GaN layer 105 formed on the GaN-based buffer layer 102; an active layer 120 formed on the first electrode layer; and a second electrode layer of a p-GaN layer 110 formed on the active layer 120.

[0017] Herein, the GaN-based buffer layer **102** can be formed having a triple-structured $\text{Al}_y\text{In}_x\text{Ga}_{1-x-y}\text{N}/\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ (Here, $0 \leq x \leq 1$, $0 \leq y \leq 1$) laminated, a double-structured $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ (Here, $0 \leq x \leq 1$) laminated, or a super-lattice-structured (SLS) $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ (Here, $0 \leq x \leq 1$) laminated.

[0018] In other words, in the inventive nitride semiconductor LED, on the substrate **101** (for example, a sapphire substrate or a SiC substrate) is grown-up the GaN-based nitride semiconductor as the GaN-based buffer layer **102**, the n-GaN layer **105** is formed as the first electrode layer, and an atomic Mg-doped p-GaN layer **110** is formed as the second electrode layer. Additionally, the active layer **120** having an InGaN/GaN multi-quantum well structure is formed in a sandwich combination structure between the first electrode layer of the n-GaN layer **105** and the second electrode layer of the p-GaN layer **110**.

[0019] Here, the active layer **120** can be formed with an $\text{In}_x\text{Ga}_{1-x}\text{N}$ well layer **106**, an $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ barrier layer **107**, an $\text{In}_x\text{Ga}_{1-x}\text{N}$ well layer **108** and an $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ barrier layer **109**. Further, between the GaN-based buffer layer **102** and the first electrode layer of the n-GaN layer **105** can be also additionally formed an undoped GaN layer or an indium-doped GaN layer **103** and **104**.

[0020] Additionally, in a process of growing-up the GaN-based buffer layer **102** on the substrate **101** at a low temperature, a metal organic chemical vapor deposition (MOCVD) equipment is used such that it is, in a growth pressure of 100-700 torr and at a low temperature of 500-800° C., grown-up to have a thickness of below 700 Å in a laminated structure such as the triple-structured $\text{Al}_y\text{In}_x\text{Ga}_{1-x-y}\text{N}/\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$, the double-structured $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ or the super-lattice-structured (SLS) $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$, etc.

[0021] At this time, for growing-up the GaN-based buffer layer **102** at the low temperature, the MOCVD equipment is used having a carrier gas of H₂, N₂ supplied while a source gas of TMGa, TMIIn, TMAI introduced and simultaneously a NH₃ gas introduced.

[0022] Further, in a high temperature process of growing-up the GaN-based single crystalline layer, on the GaN-based buffer layer **102** is, at a 900-1100° C. temperature, the undoped GaN layer or the indium-doped GaN layer **103** and **104**, and on the result thereof is again formed an atomic silicon-doped n-GaN layer **105** (over a $1 \times 10^{18}/\text{cm}^3$ concentration). Herein, the n-GaN layer **105** is used as the first electrode layer and has a carrier concentration of over $1 \times 10^{18}/\text{cm}^3$.

[0023] At this time, for growing-up the GaN-based single crystalline layer, the MOCVD equipment is used having the source gas of TMGa, TMIIn supplied at the 900-1100° C. temperature to grow-up the GaN-based single crystalline layer. Additionally, the TMGa, TMIIn source gas is introduced for supplying at the 100-700 torr pressure and a 0.1-700 μmol/min flow rate to grow-up the GaN-based single crystalline layer. At this time, a SiH₄ gas is used as a dopant gas for doping a silicon atom.

[0024] On the other hand, FIG. 2 is a sectional view illustrating a schematic construction of a nitride semiconductor LED according to a second embodiment of the present invention.

[0025] Referring to FIG. 2, in the inventive nitride semiconductor LED, on the substrate **201** (for example, the sapphire substrate or the SiC substrate) is provided the GaN-based buffer layer **202** having the triple-structured $\text{Al}_y\text{In}_x\text{Ga}_{1-x-y}\text{N}/\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ (Here, $0 \leq x \leq 1$, $0 \leq y \leq 1$), the double-structured $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ (Here, $0 \leq x \leq 1$), or the super-lattice-structured (SLS) $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ (Here, $0 \leq x \leq 1$). Additionally, on the GaN-based buffer layer **202** is formed the undoped GaN layer or the indium-doped GaN layer **203**.

[0026] Further, on the undoped GaN layer or the indium-doped GaN layer **203** are formed $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ SPS layers **204** and **206** in a sandwich structure of upper and lower parts having the undoped GaN layer or the indium-doped GaN layer **205** interposed therebetween.

[0027] On the upper $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ SPS layer **206** is formed the n-GaN layer **207** as the first electrode layer. Here, the first electrode layer of the n-GaN layer **207** has the carrier concentration of over $1 \times 10^{18}/\text{cm}^3$, and has the silicon used as the dopant.

[0028] Additionally, the nitride semiconductor LED includes, as a light emitting layer, an active layer **220** of $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$. Here, the active layer **220** can be formed in the multi-quantum well structure having an $\text{In}_x\text{Ga}_{1-x}\text{N}$ well layer **208**, an $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ barrier layer **209**, an $\text{In}_x\text{Ga}_{1-x}\text{N}$ well layer **210** and an $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ barrier layer **211**.

[0029] In the present invention, when the active layer **220** is formed, the $\text{In}_x\text{Ga}_{1-x}\text{N}$ well layers **208** and **210** and the $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ barrier layers **209** and **211** are grown-up to respectively have a thickness of less than 70 Å at a 700-800° C. growth temperature and in a N₂ atmosphere. After that, the growth temperature is increased to a range of 900-1020° C. and a Cp₂Mg doping gas is introduced so that a p-GaN layer **212** is grown-up in a 0.01-0.5 μm thickness to be used as a second electrode layer, and at this time, a mixed gas atmosphere of NH₃, H₂ as atmosphere gas is maintained with a high purity degree.

[0030] At this time, as shown in FIG. 2, the inventive nitride semiconductor LED includes the $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ SPS layers **204** and **206**. Accordingly, in order to evaluate an influence of the sandwich-structured $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ SPS layers **204** and **206** upon a crystallinity variation, a structure is grown-up not including the $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ multi-quantum well structure of the active layer **220** and the second electrode layer of the p-GaN layer **212**, and then a DC-XRD analysis is performed.

[0031] As a result of the above DC-XRD analysis, in case of a conventional nitride semiconductor having an undoped GaN/n-GaN structure as the buffer layer, a FWHM (full-width half-maximum) value of about 290 arcsec is obtained, but in case of having the inventive structure of FIG. 2, a FWHM value of about 250 arcsec is obtained. Considering the above, in case of having the sandwich-structured $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ SPS layers **204** and **206** as in the present invention, it can be appreciated that the crystallinity is improved.

[0032] Furthermore, as a result of analyzing an electrical characteristic of the nitride semiconductor LED having the structure of FIG. 2, a forward bias characteristic such as an operation voltage (VF) and the brightness, etc. is not varied. However, it can be appreciated that, when the reverse bias is

applied, a conventional reverse bias breakdown voltage is increased from “-15V” to over “-19V” so that the current leakage is improved.

[0033] The above-improved characteristic is caused by an effect of effectively reducing a dislocation formed in the substrate **201** and the GaN-based buffer layer **202** to be intruded into surface. And accordingly, it is caused by the result that the $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ multi-quantum well structure of the active layer **220** and the p-GaN layer **212** are improved in their crystallinities.

[0034] On the other hand, the present invention provides, for more improving the characteristic, the nitride semiconductor LED having the following structure.

[0035] FIG. 3 is a sectional view illustrating a schematic construction of the nitride semiconductor LED according to a third embodiment of the present invention.

[0036] As shown in FIG. 3, in the inventive nitride semiconductor LED, on a first electrode layer of a high concentration doped n^+ -GaN layer **307** is additionally grown-up a low concentration silicon of about $1 \times 10^{17}/\text{cm}^3$ doped n-GaN layer **308**. Accordingly, in an interface of the $\text{In}_x\text{Ga}_{1-x}\text{N}$ well layer **309** grown-up first in the $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ multi-quantum well structured active layer **320** grown-up at a relatively low growth temperature, a stress can be suppressed and crystallinity can be improved.

[0037] Here, in case the n-GaN layer **308** is formed with a semi-insulating GaN layer, it can also function as a role of a current prevention layer for effectively cutting off the current leakage which is, at the time of reverse bias, reversely intruded in the light emitting layer (multi-quantum well active layer).

[0038] Additionally describing, in case the nitride semiconductor LED is reversely biased, its crystallinity deterioration results in the current leakage. Accordingly, for preventing this, it can be formed in a structure having a thin semi-insulating GaN layer or a low concentration of below $1 \times 10^{18}/\text{cm}^3$ doped n-GaN layer inserted.

[0039] In other words, the inventive nitride semiconductor LED includes a substrate **301**; a GaN-based buffer layer **302** formed on the substrate **301**; a first electrode layer of an n^+ -GaN layer **307** formed on the GaN-based buffer layer **302** and containing a high concentration of dopants; an n-GaN layer **308** formed on the first electrode layer and containing a low concentration of dopants; an active layer **320** formed on the n-GaN layer **308**; and a second electrode layer of a p-GaN layer **313** formed on the active layer **320**.

[0040] Here, on the substrate **301** is provided the GaN-based buffer layer **302** having the triple-structured $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ (Here, $0 \leq x \leq 1$, $0 \leq y \leq 1$), the double-structured $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ (Here, $0 \leq x \leq 1$) or the super-lattice-structured (SLS) $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ (Here, $0 \leq x \leq 1$). Additionally, on the GaN-based buffer layer **302** is formed an undoped GaN layer or an indium-doped GaN layer **303**.

[0041] Further, on the undoped GaN layer or the indium-doped GaN layer **303** are formed $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ SPS layers **304** and **306** in a sandwich structure of upper and lower parts having the indium-doped GaN layer **305** interposed therebetween.

[0042] On the upper $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ SPS layer **306** is formed the n^+ -GaN layer **307** as the first electrode layer. Here, the first electrode layer of the n^+ -GaN layer **307** has the carrier concentration of over $1 \times 10^{18}/\text{cm}^3$ and has silicon used as the dopant.

[0043] Additionally, the nitride semiconductor LED includes, as the light emitting layer, the active layer **320** of $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$. Here, the active layer **320** can be formed to have the multi-quantum well structure having an $\text{In}_x\text{Ga}_{1-x}\text{N}$ well layer **309**, an $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ barrier layer **310**, an $\text{In}_x\text{Ga}_{1-x}\text{N}$ well layer **311** and an $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ barrier layer **312**.

[0044] On the other hand, in a fabrication method of the nitride semiconductor LED according to the present invention, when the undoped GaN layer and the indium-doped GaN layer **305** and **306**, and the first electrode layer of the n^+ -GaN layer **307** are grown-up, besides a high purity degree of NH_3 and H_2 carrier gases, a N_2 gas is mixed and used as the carrier gas. In the above-processed case, a thickness regularity doped and grown-up is improved. Additionally, from analysis of a forward and reverse electrical characteristic, an operation voltage and a reverse breakdown voltage can be obtained having a very regular dispersion distribution in a wafer.

INDUSTRIAL APPLICABILITY

[0045] As described above, the inventive semiconductor LED and its fabrication method can reduce the crystal defect caused by the difference of the thermal expansion coefficient and the lattice constant in the substrate and the GaN-based single crystalline layer grown-up on the substrate, and can improve the GaN-based single crystalline layer in its crystallinity. Accordingly, the present invention has an advantage in which the nitride semiconductor LED can be improved in its performance and assured in its reliability.

1. A nitride semiconductor LED, comprising:

a substrate;

a GaN-based buffer layer formed on the substrate;

$\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ short period superlattice (SPS) layers formed on the GaN-based buffer layer in a sandwich structure of upper and lower layers having an undoped GaN layer or an indium-doped GaN layer interposed therebetween (where, $0 \leq y \leq 1$);

a first electrode layer of an n-GaN layer formed on the upper $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ SPS layer;

an active layer formed on the first electrode layer; and

a second electrode layer of a p-GaN layer formed on the active layer;

2. The nitride semiconductor LED of claim 1, wherein the GaN-based buffer layer has a triple-structured $\text{Al}_y\text{In}_x\text{Ga}_{1-x-y}\text{N}/\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ laminated (Here, $0 \leq x \leq 1$, $0 \leq y \leq 1$), a double-structured $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ laminated (Here, $0 \leq x \leq 1$), or a super-lattice-structured (SLS) $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ laminated (Here, $0 \leq x \leq 1$).

3. The nitride semiconductor LED of claim 1, further comprising the undoped GaN layer or the indium-doped GaN layer on the GaN-based buffer layer.

4. A nitride semiconductor LED, comprising:
 a substrate;
 a GaN-based buffer layer formed on the substrate;
 an undoped GaN layer or an indium-doped GaN layer formed on the GaN-based buffer layer;
 $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ short period superlattice (SPS) layers formed on the undoped GaN layer or the indium-doped GaN layer, in a sandwich structure of upper and lower layers having the undoped GaN layer or the indium-doped GaN layer interposed therebetween (Here, $0 \leq y \leq 1$);
 a first electrode layer of an n^+ -GaN layer formed on the upper $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ SPS layer and containing a high concentration of dopants;
 an n-GaN layer formed on the first electrode layer and containing a low concentration of dopants;
 an active layer formed on the n-GaN layer; and
 a second electrode layer of a p-GaN layer formed on the active layer.
5. The nitride semiconductor LED of claim 4, wherein the GaN-based buffer layer has a triple-structured $\text{Al}_y\text{In}_x\text{Ga}_{1-x-y}\text{N}/\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ laminated (Here, $0 \leq x \leq 1$, $0 \leq y \leq 1$), a double-structured $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ laminated (Here, $0 \leq x \leq 1$), or a super-lattice-structured (SLS) $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ laminated (Here, $0 \leq x \leq 1$).
6. A nitride semiconductor LED, comprising:
 a substrate;
 a GaN-based buffer layer formed on the substrate;
 a first electrode layer of an n^+ -GaN layer formed on the GaN-based buffer layer and containing a high concentration of dopants;
 an n-GaN layer formed on the first electrode layer and containing a low concentration of dopants;
 an active layer formed on the n-GaN layer; and
 a second electrode layer of a p-GaN layer formed on the active layer.
7. The nitride semiconductor LED of claim 6, wherein the dopant concentration of the n^+ -GaN layer is more than $1 \times 10^{18}/\text{cm}^3$.
8. The nitride semiconductor LED of claim 6, wherein the dopant concentration of the n-GaN layer is less than $1 \times 10^{18}/\text{cm}^3$.
9. The nitride semiconductor LED of claim 6, wherein the dopant concentration of the n-GaN layer is $1 \times 10^{17}/\text{cm}^3$.
10. The nitride semiconductor LED of claim 6, wherein the GaN-based buffer layer has a triple-structured $\text{Al}_y\text{In}_x\text{Ga}_{1-x-y}\text{N}/\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ laminated (Here, $0 \leq x \leq 1$, $0 \leq y \leq 1$), a double-structured $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ laminated

- (Here, $0 \leq x \leq 1$), or a super-lattice-structured (SLS) $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ laminated (Here, $0 \leq x \leq 1$).
11. The nitride semiconductor LED of claim 6, further comprising $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ short period superlattice (SPS) layers formed on the GaN-based buffer layer in a sandwich structure of upper and lower parts having an undoped GaN layer or an indium-doped GaN layer interposed therebetween (Here, $0 \leq y \leq 1$).
12. A fabrication method of a nitride semiconductor LED, the method comprising the steps of:
 growing-up a GaN-based buffer layer on a substrate;
 forming $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ short period superlattice (SPS) layers on the GaN-based buffer layer in a sandwich structure of upper and lower parts having an undoped GaN layer or an indium-doped GaN layer interposed therebetween (Here, $0 \leq y \leq 1$);
 forming a first electrode layer of an n^+ -GaN layer containing a high concentration of dopants, on the upper $\text{Al}_y\text{Ga}_{1-y}\text{N}/\text{GaN}$ SPS layer;
 forming an active layer on the first electrode layer; and
 forming a second electrode layer of a p-GaN layer on the active layer.
13. The fabrication method of claim 12, further comprising the step of forming an n-GaN layer containing a low concentration of dopants, between the first electrode layer of the n^+ -GaN layer and the active layer.
14. The fabrication method of claim 12, wherein the GaN-based buffer layer is, using a MOCVD equipment, grown-up to have a 50-800 Å thickness at a 500-800° C. temperature and in an atmosphere having H_2 and N_2 carrier gases supplied while having TMGa, TMIIn, TMAI source gas introduced and simultaneously having NH_3 gas introduced.
15. The fabrication method of claim 12, wherein the GaN-based buffer layer is grown-up with a 5-300 $\mu\text{mol}/\text{min}$ flow rate of the TMGa, TMIIn, TMAI source gas and a 100-700 torr growth pressure.
16. The fabrication method of claim 12, wherein the GaN-based buffer layer has a triple-structured $\text{Al}_y\text{In}_x\text{Ga}_{1-x-y}\text{N}/\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ laminated (Here, $0 \leq x \leq 1$, $0 \leq y \leq 1$), a double-structured $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ laminated (Here, $0 \leq x \leq 1$), or a super-lattice-structured (SLS) $\text{In}_x\text{Ga}_{1-x}\text{N}/\text{GaN}$ laminated (Here, $0 \leq x \leq 1$).
17. The fabrication method of claim 12, further comprising the step of forming an undoped GaN layer or an indium-doped GaN layer on the GaN-based buffer layer.
18. The fabrication method of claim 12, wherein the dopant concentration of the n^+ -GaN layer is more than $1 \times 10^{18}/\text{cm}^3$.
19. The fabrication method of claim 13, wherein the dopant concentration of the n-GaN layer is $1 \times 10^{17}/\text{cm}^3$.
20. The fabrication method of claim 13, wherein the n-GaN layer is formed with a semi-insulating layer.

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